

In place of PTO-1449 Form		U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		Complete if Known	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> <i>(use as many sheets as necessary)</i>					
SHEET	1	OF	1	Application Number	10/722,218
				Filing Date	November 25, 2003
				Applicant(s)	Shui-Ming Cheng, et al.
				Art Unit	2811
				Examiner Name	TBD
				Attorney/Docket Number	24061.149

OTHER PRIOR ART		
Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume, issue number(s), publisher, city/country where published
KJ/00	AA	SHIMIZU, A., et al., "Local Mechanical-Stress Control (LMC): A New Technique for CMOS-Performance Enhancement", IEEE, 2001, 4 pages.

Examiner Signature Ronald A. Oylee Date Considered 16 Dec 04

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.